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# Study of Pentacene-Based Organic Thin Film Transistor with PMMA as Insulator

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#### 1. Introduction

Organic materials are generally used in many electrical devices like as light emitting diodes [1], thin film transistors [2-3], and photo-detectors [4]. Due to variety of materials, fabrication methods, and amazing characteristics, the organic electrical devices attract many researchers to jump into this field. For organic thin film transistors, many different materials, structures, and special modification methods were used to improve the characteristics of devices. Nowadays, the characteristics of OTFT were almost the same as amorphous silicon (A-Si) which was commonly adapted in the modern liquid crystal display (LCD). Pentacene-based OTFT with a field-effect mobility greater than  $1 \text{ cm}^2/(\text{V} \cdot \text{s})$  and an on/off current ratio over  $10^8$  have been demonstrated by several groups[5-7].

In this study, we used Poly(methyl methacrylate) PMMA as insulator to substitute  $SiO_2$  and conferred the transfer characteristics of PMMA-insulator OTFT. We also compared the transfer characteristics of PMMA-insulator OTFT with the characteristics of  $SiO_2$ -insulator OTFT.

#### 2. Experiments

The PMMA-insulator OTFTs structure was shown in Fig. 1. The OTFTs were fabricated on a high doping n-type silicon substrate. PMMA was dissolved in Toluene with a concentration of 8 wt% and then spin-coated on high doping n-type silicon substrate to form a 300 nm thin film to serve as organic insulator. SiO<sub>2</sub> is thermally grown on high doping n-type silicon substrate and the thickness of SiO<sub>2</sub> is also 300 nm. The molecular structures of PMMA and Pentacene were shown in Fig. 1. Pentacene thin films are grown on SiO2 and PMMA by vacuum evaporation under a base pressure of approximately  $5*10^{-6}$  torr, respectively. The thickness of Pentacene is 60 nm. After depositing Pentacene thin film, for the drain source and gate electrodes, 200-nm-thick Au layer, are deposited through a shadow mask by a thermal evaporator. The channel length and

width of these devices are 50  $\mu$ m and 1000  $\mu$ m, respectively. The characteristics of these devices are measured with Keithley 4200 system.

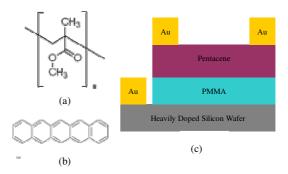


Fig.1 (a) PMMA molecular structure, (b) Pentacene structure, (c) OTFT structure

#### 3. Results and discussion

Fig. 2 shows the transfer characteristics of the PMMA-insulator Pentacene OTFT and SiO<sub>2</sub>-insulator Pentacene OTFT. From this figure, it can be found the drain current  $I_{DS}$  of PMMA-insulator OTFT is higher than the drain current  $I_{DS}$  of SiO<sub>2</sub>-insulator OTFT on the same gate voltage V<sub>G</sub>.

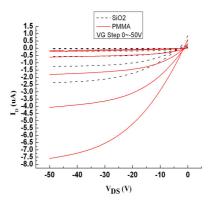
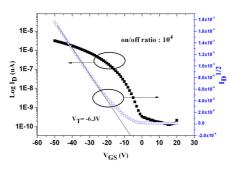
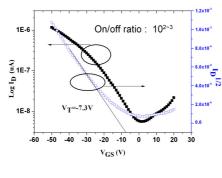


Fig.2 Transfer characteristics of OTFTs with PMMA and OTFTs with SiO2 in the same Pentacene-deposited process

Fig. 3a and Fig. 3b present the transfer characteristics of PMMA-insulator OTFT and SiO2-insulator OTFT when  $V_{DS}$  (the voltage between drain and source) is -50 V, respectively. It can be found that the on/off current of PMMA-insulator OTFT and SiO2-insulator OTFT are  $10^{2-3}$  and  $10^4$ , respectively. It also can be found that the threshold voltage  $V_T$  of PMMA-insulator OTFT and SiO2-insulator OTFT are -6.3V and -7.3V, respectively. The mobility of PMMA-insulator OTFT and SiO2-insulator are 0.215 cm<sup>2</sup>/V · s and 0.0372 cm<sup>2</sup>/V · S, respectively.







(b)

Fig.3 (a)transfer characteristics of OTFT with PMMA, (b)transfer characteristics of OTFT with SiO2 in the same Pentacene-deposited process.

For the same Pentacene-deposited process of OTFT, we found that the all transfer characteristics of PMMA-insulator OTFT are than transfer characteristics greater of SiO2-insulator OTFT. Fig. 4 shows the X-ray diffraction spectra of pentacene thin films deposited on PMMA and SiO<sub>2</sub>. From this figure, it can be found that the peak intensity of Bragg reflection of pentacene thin film on PMMA is stronger than pentacene thin film on SiO2 very much. It means that the quality of Pentacene thin film on PMMA is greater than Pentacene thin film on SiO<sub>2</sub>. The intensity of X-ray diffraction influences on the mobility of OTFT and it is why

the mobility of PMMA-insulator OTFT is higher than the mobility of SiO<sub>2</sub>-insulator OTFT.

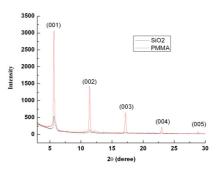


Fig.4 XRD spectra of Pentacene thin film on PMMA and on  ${\rm SiO}_2$ 

4. Conclusion

In this experiment, it was found that the all transfer characteristics of Pentacene-based OTFT with PMMA are greater than Pentacene-based OTFT with SiO2. Threshold voltage  $V_T$  of OTFT with PMMA as insulator is smaller than OTFT with SiO<sub>2</sub> and the mobility of OTFT with PMMA is higher than OTFT with SiO<sub>2</sub>. We also used XRD to measure the diffraction intensity to study the crystalline quality of Pentacene thin film on PMMA and Pentacene thin film on SiO<sub>2</sub>. For the flexible substrate, PMMA will be a good material for insulator.

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